

Notice of References CitedApplication/Control No.
10/063,134Applicant(s)/Patent Under
Reexamination
CHANG ET AL.Examiner
DuyVu n DeoArt Unit
1765

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,387,814	05-2002	Chen, Chien-Wei	438/700
	B	US-6,248,631	06-2001	Huang et al.	438/260
	C	US-6,569,735	05-2003	Su, Chun-Lien	438/257
	D	US-6,391,718	05-2002	Jeng, Pei-Ren	438/258
	E	US-6,576,514	06-2003	Liu et al.	438/259
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP10-84052-A	03-1998	Japan	Tsutomu	H01L 21/8247
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Wolf et al., Silicon Processing for the VLSI Era, Vol. 1, 1986, 1986, pg 529.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.